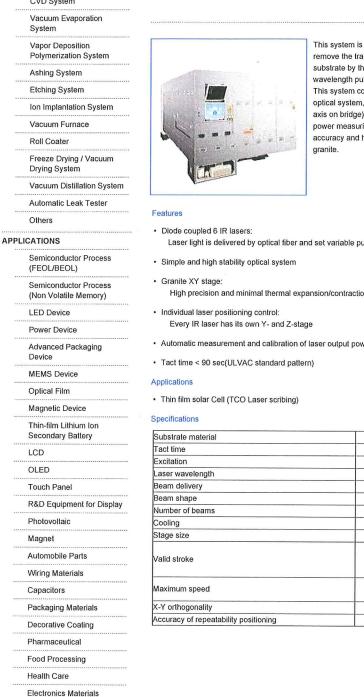
LABORATORY CO., LTD.

IPR2013-00066





CONTACT US

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This system is a single-substrate laser scribing system that is used to remove the transparent electrode (TCO) films formed on the glass substrate by the laser ablation method using the near-infrared wavelength pulse oscillating laser.

This system consists of 6 IR lasers, 6 sets of laser light collection optical system, bridge type XY stage (X-axis: lower axis, Y-axis: upper axis on bridge), substrate conveyor mechanism, dust collector, laser power measuring instrument and control systems. It is achieved high accuracy and high stability for using fiber lasers and a stage made of

- Laser light is delivered by optical fiber and set variable pulse width
- High precision and minimal thermal expansion/contraction
- · Automatic measurement and calibration of laser output power

Substrate material	W1400 x D1100 x t=3-5mm		
Tact time	< 90 sec. (ULVAC standard pattern)		
Excitation	Laser Diode		
Laser wavelength	About 1.06µm		
Beam delivery	Optical Fiber		
Beam shape	About 50-70µm circle		
Number of beams	Air cooling		
Cooling	Air cooling		
Stage size	W2420mm x L4570mm x H2100mm		
	X axis(upper axis): 2000mm		
Valid stroke	Y axis(lower axis): 1260mm		
	Z axis(mounted on Y stage): 50mm		
Maximum speed	X:1000mm/sec		
Maximum speed	Y:600mm/sec.		
X-Y orthogonality	Below 5µm/500mm		
Accuracy of repeatability positioning	Below +/-10µm		

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http://www.ulvac.co.jp/products_e/equipment/products/others/ult-1400

Functional Materials

PRODUCT CATEGORY	APPLICATIONS • Semiconductor Process (EEOL/RECOL)	Vacuum Pump • Dry Pump • Oil Patana Pump	Sputtering Targets For FPD For Seminardurber	Field Service for Equipment Flied Service
 CVD System Vacuum Evaporation System Vapor Deposition Polymerization System Ashing System Etching System Ion Implantation System Vacuum Furnace Roll Coater Freeze Drying / Vacuum Drying System Vacuum Distillation System Vacuum Distillation System Others 	(FEOL/BEOL) Semiconductor Process (Non Volatile Memory) LED Device Power Device Advanced Packaging Device MEMS Device Optical Film Magnetic Device Thin-film Lihlum Ion Secondary Battery LCD OLED Touch Panel R&D Equipment for Display Photovoltaic Magnet Automobile Parts Varing Materials Capacitors Packaging Materials Decorative Coating Pharmaceutical Food Processing Health Care Electronics Materials Functional Materials Functional Materials Functional Materials Functional Materials Functional Materials Functional Materials Functional Materials Home Appliance	 Off Rotary Pump Machanical Booster Pump Ion Pump Turbo Molecular Pump Ori Diffusion Pump Cryo Pump Titanium Getter Pump Titanium Getter Pump Titanium Gauge Process Gas Monitor Leak Detector Thin Film Measurement/Deposition Controller Vacuum Valve Parts for Ultra-High Vacuum Power Supply Transfer Robol Software Catalog Download Drawing Data Download Termination of Production and Maintenance 	 For Semiconductor For Photovoltaic ITO Target IGZO Target Evaporation Deposition Materials High Performance Materials [Ta][Nb] Sheet [Ta][Nb] Tube/Pipe [Ta][Nb][Zr] Reactor Vessels [Ta][Nb][Zr]	 Gloobal CIP Factory Outsourcing Recycling / Cleaning / Reusing Resources Maintenace for Component Pump Maintenance Service JCSS Calibration Service (Vacuum Gauge) Terrrination of Production and Maintenance Parts Supply Surface Treatment MEMS Foundry Service Analysis Service Used Equipment/Refurbish
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http://www.ulvac.co.jp/products_e/equipment/products/others/ult-1400